

## IMPORTANT DATES

June 16-18, 2010	Conference
June 15, 2010	Tutorials
April 21, 2010	Acceptance notification
April 9, 2010	Deadline for abstract submission
<b>March 2010</b>	<b>Call for papers</b>
November 2009	1 <sup>st</sup> announcement

REGISTRATION FEES	Conference	Conference + Tutorials
SFV Member	350 €	500 €
Non-SFV Member	400 €	550 €
Student	250 €	300 €
Additional charge after May 31	50 €	50 €

*Fees include coffee breaks, lunches (excepted on Friday), conference dinner and the abstract booklet.*

One page abstract of accepted papers will be published in the abstract booklet and given to all registered participants at the beginning of the conference.

Please submit your one page abstract before 9 April on  
[www.vide.org/miatec2010.html](http://www.vide.org/miatec2010.html)

## CONTACT, CONFERENCE SECRETARY

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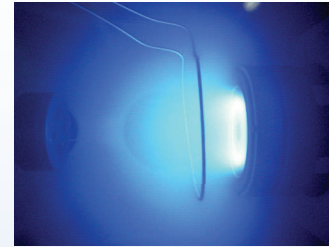
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# Call for Papers



# MIATEC 2010

*Magnetron,  
Ion processing  
& Arc Technologies  
European Conference*

**June 15-18, 2010**

**Metz, France**

Congress Centre

**Deadline:  
9 April, 2010**

### Topics:

- Sources
- Modelling
- Diagnostics
- Related technologies
- Applications
- Industrial hot topics

**[www.vide.org/miatec2010.html](http://www.vide.org/miatec2010.html)**

*In connection with SVTM 2010,  
International Exhibition on Vacuum  
and Surface Engineering*



Organized by Société Française du Vide

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## SCOPE

The thin film deposition by **PVD** (Physical Vapor Deposition) is being drastically improved over the last decade by the rise of novel technologies such as **IPVD magnetrons** (Ionized Physical Vapor Deposition), **HPPMS** (High Power Pulsed Magnetron Sputtering), **IBAD** (Ion Beam Assisted Deposition), **non equilibrium low current arc discharges**, **very high pressure arc discharges**, **overheat reduction of arcs**, etc.



These technologies open the way for tailoring the film properties according to customer's requirements and for environmental friendly processes compared to classical wet deposition ones.

Taking into account the European dimension of the scientific and engineering community working in this area, it comes obvious that the next meeting – **MIATEC 2010** – has to be the echo of their research and the catalyst for efficient exchanges between the academic and industrial fields thus contributing to technological transfers.

**MIATEC 2010** work program is planned to be parallel with two others important meetings, taking place jointly, namely **SVTM 2010** (*International exhibition for vacuum and surface engineering*) & **A3TS 2010** (*38<sup>th</sup> Congress of thermal treatment and surface treatment*).

Tiberiu Minea  
*Chair of MIATEC 2010*

## SCIENTIFIC COMMITTEE

**V. Antoni** - Consortio RFX, Padua (I)

**V. Bellido-Gonzalez** - Gencoa, Liverpool (UK)

**N. Brenning** - KTH, Stockholm (S)

**D. Depla** - Univ. Gent (B)

**L. Fulcheri** - Ecole des Mines, Sophia-Antipolis (F)

**K. Hevesi** - AGC Flat Glass, Brussels (B)

**S. Lucas** - Univ. Namur (B)

**W. Moëller** - Dresden Univ. (D)

**F. Richter** - TU Chemnitz (D)

**L. Roux** - IBS, Peynier (F)

**S. Spencer** - NCT, ME (USA)

**J. Vlcek** - Pilzen Univ. (CZ)

**Chair** Tiberiu Minea - LPGP, Univ. Paris-Sud XI, Orsay (F)

## INVITED SPEAKERS

• **Xavier BADICHE**  
HEF Groupe (F)

• **Ralf BANDORF**  
Fraunhofer Institute (D)

• **Wouter LEROY**  
University of Ghent (B)

• **Savino LONGO**  
University of Bari (I)

• **Serguei MIKHAILOV**  
Haute Ecole Arc (CH)

• **Frank TORREGROSA**  
Ion Beam Services (F)

• **Catalin VITELARU**  
University of Iași (RO)

• **Jiri VYSKOCIL**  
HVM Plasma (CZ)

*The working language for MIATEC 2010 is English (excepted for tutorials).*

## SPECIAL SESSION: « INDUSTRIAL HOT TOPICS »

*Chair: Victor BELLIDO-GONZALEZ (Gencoa, UK)*

'Industrial Hot Topics' session is devoted to **flash presentations** focusing on the scientific approaches, innovative insights, and recent R&D advances related to the conference activities. **This session is open to the companies attending MIATEC 2010 as well as SVTM exhibitors.** The registration as speaker is possible on MIATEC 2010, choosing 'Abstract submission' and ticking the item 'Industrial Hot Topics'.

*Note that an abstract is required for oral presentation.*

## TUTORIALS

The MIATEC 2010 Conference is preceded by **one tutorial day** (June 15) dedicated to main fields of interest « magnetrons », « arcs » and « ion assisted processing ». **Tutorials will be given in French.**

## MIATEC 2010 VENUE

Just 82 minutes from Paris by TGV, close to Luxembourg, Germany, and Belgium, Metz is ideally located. Its strategic position and high-level amenities has turned it into a **true European crossroads.**

In a natural setting, the Congress Center is easily reached by car or by public transport.

SFV will organize a shuttle from and to Metz railway station.

